

ABSTRACT

The end of a nozzle (23) of a laser-excited plasma light source is made of a specific material, such as silicon Si, the transmittance of which to EUV light is higher than those of heavy metals. Therefore, even if the temperature of the end of the nozzle is higher than the melting point of the specific material because of the high temperature of the plasma produced around the focal point (24), the end of the nozzle is therefore eroded, and sputtered particles of the material adhere to a light-collecting mirror provided near the nozzle, the degradation of the reflectance of the light-collecting mirror (PRM) is mitigated compared to the transmittance of the sputtered particles (specific material) to EUV light is higher than those of heavy metals.